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Hisatsugu Kurita, Shibata-shi, JAPAN; Manabu Hirasawa, Shibata-shi, JAPAN; Hiromi Nagahama, Shibata-shi, JAPAN;Koji Izumome, Shibata-shi, JAPAN; Takao Ino, Yokohama-shi, JAPAN; Jyunsei Yamabe, Yokohama-shi, JAPAN; Naoya Hayamizu, Yokohama-shi, JAPAN; Naoaki Sakurai, Yokohama-shi, JAPAN; Naoaki Sakurai, Yokohama-shi, JAPAN; "CONTINUING DATA" "FOREIGN APPLICATIONS" JAPAN 2002-259579 09/05/2002 JAPAN 2002-259579 10/15/2002 JAPAN 2003-005323 01/14/2003 IF REQUIRED, FOREIGN FILING LICENSE GRANTED					
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Foreign Priority claimed 35 USC 119 (a-d) conditions	yes no Met after Allowance Mider's/Signature Initials	STATE OR	SHEETS	TOTAL	INDEPENDENT
met Verified and		COUNTRY	DRAWING 7	CLAIMS 4	CLAIMS 1
ADDRESS 22428 FOLEY AND LARDNE SUITE 500 3000 K STREET NW WASHINGTON, DC 20007			•		
Silicon wafer cleaning	method				